HIGH POWER LASER BEAM PROFILER SYSTEM SOLUTION / HIGH PERFORMANCE NFP MEASUREMENT SYSTEM

SOPHISTICATED OPTICAL BEAM NFP MEASUREMENT SYSTEM FOR HIGH POWER LASER

Optical beam profile and NFP measurement system especially targeting for high power laser

Sophisticated optical beam NFP measurement system for high power laser is a highperformance optical beam profile measurement system targeting for ~10W class high power

laser. Sophisticated NFP measurement optics for high power laser **M-Scope type HS** is used. The light flux emitted from high power laser sample is attenuated by beam sampler unit after passing through objective lens, and is further attenuated by ND filter at subsequent stage. The NFP image that has been attenuated to appropriate beam power is captured and image processing analysis is performed. In addition, the radiation angle distribution (FFP) can be measured in a narrow angle range by measuring without the objective lens.

[Features]

OM-Scope type HS, sophisticated NFP measurement optics for high power laser

- Attenuation of incident beam with two-stage beam sampler and ND filters
- Can be used with a variety of high power resistant objectives (M-Plan Apo NUV/NIR series)
- Optical beam analysis module AP013, specially designed high-functional image processing software for optical beam profile analysis
 All-in-one package of PC, optical beam analysis software, detector driver, correction data.
 - High-performance image processing software for optical beam profile measurement Optimetrics BA Standard is pre-installed.

[Standard component]

OHigh power laser NFP measurement optics laser selection

- 850~940nm: M-Scope type HS/NIR
- 400~650nm: M-Scope type HS/BL

*Please specify the measurement wavelength because AR coating to some optical parts is required.

OAvailable detector

• 400-1100nm : High resolution CMOS detector ISA071/ISA071GL Optical beam analysis module AP013

 PC for image processing, optical beam analysis software Optometrics BA Standard, detector driver, calibration data, USB key

OAccessories

• Cables, instruction manuals, etc.

[Detector selection, angle coverage, field of view, pixel resolution (approx. value)]

Detector	High resolution CMOS detector ISA071/ISA071GL	
Spectral range	400~1100nm	
Sensor size	1/1.8 inch	
Total pixels	2048×1536	
Pixels pitch	3.45µm	
Magnification	Field of view	Resolution
	(unit:mm)	(unit:µm)
5×	1.41×1.05	0.69
10×	0.70×0.52	0.345
20×	0.35×0.26	0.173
50×	0.14×0.1	0.069
100×	0.07×0.05	0.035
FFP meas.	Meas. angle	Resolution
(unit:degree)	±1.01x±0.75	0.001

[Option]

Objective lens selection

- Select the objective lens according to the optical magnification (field of view), pixel resolution, N.A., wavelength, etc.
- Option for optics (for M-Scope type HS)
 - 2× intermediate lens port **MS-OP011-RL2** Intermediate lens unit that doubles the overall magnification
 - 1/2× intermediate lens port **MS-OP011-RLH** Intermediate lens unit that halves the overall magnification
 - Coaxial epi-illumination port **MS-OP011-CEP** Coaxial epi-illumination port with removable half mirror
 - Dummy filters MS-OP016-DF
 wedge true dummy filters for pulse /lew power measurem

wedge type dummy filters for pulse/low power measurement $\bigcirc ND$ filter (for M-Scope type HS, dedicated $30\phi)$

Visible (400~700nm): NDF 30-5 (5 types per set)
 NIR (700~1100nm): NDF NIR 30-5 (5 types per set)
 Coaxial epi-illumination light source

- Visible~NIR: LED epi-illumination system
- Optics bench
 - Optics bench for fiber measurement with manual stages
 - Vertical setting optics bench

*Pixel resolution: The measurement length equivalent to 1 pixel of the detector calculated from filed of view and sensor pitch of the detector.

*The optical magnification when using **MS-OP011-RL2** is 2 times the magnification in the table on the left, and the actual field of view and pixel resolution are 1/2. The maximum optical magnification is 200x when using a 100x objective lens.

* The optical magnification when using the **MS-OP011-RLH** is 1/2 of each magnification

in the table on the left, and the actual field of view and pixel resolution are 2 times.

[Component selection of high power laser NFP measurement system]



